

Title (en)

SUBRESOLUTION SILICON FEATURES AND METHODS FOR FORMING THE SAME

Title (de)

SILIZIUM MIT SUBRESOLUTIONSEIGENSCHAFTEN UND HERSTELLUNGSVERFAHREN DAFÜR

Title (fr)

DÉTAILS DE SILICIUM EN SOUS-RÉSOLUTION ET PROCÉDÉS DE FORMATION

Publication

**EP 2041781 A1 20090401 (EN)**

Application

**EP 07810048 A 20070628**

Priority

- US 2007015146 W 20070628
- US 48680006 A 20060714

Abstract (en)

[origin: WO2008008204A1] Novel etch techniques are provided for shaping silicon features below the photolithographic resolution limits. FinFET devices are defined by recessing oxide (102) and exposing a silicon protrusion (124) to an isotropic etch, at least in the channel region. In one implementation, the protrusion (124) is contoured by a dry isotropic etch having excellent selectivity, using a downstream microwave plasma etch.

IPC 8 full level

**H01L 21/336** (2006.01); **H01L 29/786** (2006.01)

CPC (source: EP KR US)

**H01L 29/66795** (2013.01 - EP KR US); **H01L 29/785** (2013.01 - KR); **H01L 29/7851** (2013.01 - EP KR US); **H01L 29/7853** (2013.01 - KR);  
**H01L 29/7854** (2013.01 - KR); **H10B 12/056** (2023.02 - KR); **H10B 12/31** (2023.02 - KR); **H10B 12/36** (2023.02 - KR);  
**H01L 29/7853** (2013.01 - EP US); **H01L 29/7854** (2013.01 - EP US); **H10B 12/056** (2023.02 - EP US); **H10B 12/31** (2023.02 - EP US);  
**H10B 12/36** (2023.02 - EP US)

Citation (search report)

See references of WO 2008008204A1

Designated contracting state (EPC)

DE GB IT

Designated extension state (EPC)

AL BA HR MK RS

DOCDB simple family (publication)

**WO 2008008204 A1 20080117**; CN 101490821 A 20090722; CN 101490821 B 20130123; EP 2041781 A1 20090401;  
JP 2009544150 A 20091210; JP 5391423 B2 20140115; KR 101403509 B1 20140609; KR 20090039783 A 20090422;  
US 2008014699 A1 20080117; US 2010148234 A1 20100617; US 2012061740 A1 20120315; US 7678648 B2 20100316;  
US 8084845 B2 20111227; US 8981444 B2 20150317

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**US 2007015146 W 20070628**; CN 200780025866 A 20070628; EP 07810048 A 20070628; JP 2009519450 A 20070628;  
KR 20097003076 A 20070628; US 201113302090 A 20111122; US 48680006 A 20060714; US 71312510 A 20100225